

APPLICATION
FOR
UNITED STATES LETTERS PATENT

PATENT APPLICATION

SPECIFICATION

TO ALL WHOM IT MAY CONCERN:

Be it known that Peidong Wang of 6 Dove Lane,
Billerica, MA 01862, Parviz Tayebati of 2 Commonwealth
Avenue , 15A, Boston, MA 02116 and Daryoosh Vakhshoori of 10
Rogers Street, Apt. 205, Cambridge, MA 02142 have invented
certain improvements in TUNABLE FABRY-PEROT FILTER AND
TUNABLE VERTICAL CAVITY SURFACE EMITTING LASER, of which the
following description is a specification.

PS/CORE84.CVR

TUNABLE FABRY-PEROT FILTER AND
TUNABLE VERTICAL CAVITY SURFACE EMITTING LASER

Reference To Pending Prior Patent Application

5 This is a continuation-in-part of pending prior
U.S. Patent Application Serial No. 09/750,434, filed
12/28/00 by Peidong Wang et al. for TUNABLE FABRY-PEROT
FILTER AND TUNABLE VERTICAL CAVITY SURFACE EMITTING
LASER (Attorney's Docket No. CORE-67), which is in turn
10 a continuation-in-part of U.S. Patent Application
Serial No. 09/105,399, filed 06/26/98, ^{now Pat. No. 6,438,144,} by Parviz
Tayebati et al. for MICROELECTROMECHANICALLY TUNABLE,
CONFOCAL, VERTICAL CAVITY SURFACE EMITTING LASER AND
FABRY-PEROT FILTER (Attorney's Docket No. CORE-33).

15 The two aforementioned patent applications are
hereby incorporated herein by reference.

Field Of The Invention

20 This invention relates to photonic devices in
general, and more particularly to tunable filters and
tunable lasers.

Background Of The Invention

5 Tunable Fabry-Perot filters and tunable vertical
cavity surface emitting lasers (VCSEL's) have recently
generated considerable interest in the art. This is
because these devices are believed to have application
for a wide range of different optical components and
systems, e.g., wavelength division multiplexing (WDM)
fiber optic systems, switches, routers, highly compact
spectroscopic interferometers, optical trans-receivers,
10 etc.

15 In some tunable Fabry-Perot filters and in some
tunable VCSEL's, tuning is achieved by using an
electrostatic field to move a top mirror relative to a
bottom mirror, whereby to change the length of the
Fabry-Perot cavity and hence tune the wavelength of the
device.

20 While such a construction is advantageous in that
it provides a fast and easy way to tune the device, in
practice it has been found that the tuning range of the
device is frequently limited by the electrostatic
elements used to tune the device.

Summary Of The Invention

Accordingly, one object of the present invention is to provide an improved tunable Fabry-Perot filter.

Another object of the present invention is to provide an improved tunable VCSEL.

These and other objects are addressed by the present invention.

In one form of the invention, there is provided a tunable Fabry-Perot filter which comprises a bottom mirror mounted to the top of a substrate, a bottom electrode mounted to the top of the bottom mirror, a thin membrane support atop the bottom electrode, a top electrode fixed to the underside of the thin membrane support, a reinforcer fixed to the outside perimeter of the thin membrane support, and a confocal top mirror set atop the thin membrane support, with an air cavity being formed between the bottom mirror and the top mirror, wherein the top electrode and the bottom electrode are spaced further apart from one another than the top mirror is spaced from the bottom mirror.

In another form of the invention, there is provided a tunable VCSEL which comprises a bottom mirror mounted to the top of a substrate, a gain region

mounted to the top of the bottom mirror, a bottom
electrode mounted to the top of the gain region, a thin
membrane support atop the bottom electrode, a top
electrode fixed to the underside of the thin membrane
support, a reinforcer fixed to the outside perimeter of
the thin membrane support, and a confocal top mirror
set atop the thin membrane support, with an air cavity
being formed between the bottom mirror and the top
mirror, wherein the top electrode and the bottom
electrode are spaced further apart from one another
than the top mirror is spaced from the bottom mirror.

And in another form of the invention, there is
provided a tunable Fabry-Perot filter which comprises a
bottom mirror mounted to the top of a substrate, a
bottom electrode mounted to the top of the bottom
mirror, a thin membrane support atop the bottom
electrode, a top electrode fixed to the underside of
the thin membrane support, a reinforcer fixed to the
outside perimeter of the thin membrane support, and a
confocal top mirror set atop the thin membrane support,
with an air cavity being formed between the bottom
mirror and the top mirror, wherein the top electrode
and the bottom electrode extend toward one another.

And in another form of the invention, there is provided a tunable VCSEL which comprises a bottom mirror mounted to the top of a substrate, a gain region mounted to the top of the bottom mirror, a bottom electrode mounted to the top of the gain region, a thin membrane support atop the bottom electrode, a top electrode fixed to the underside of the thin membrane support, a reinforcer fixed to the outside perimeter of the thin membrane support, and a confocal top mirror set atop the thin membrane support, with an air cavity being formed between the bottom mirror and the top mirror, wherein the top electrode and the bottom electrode extend toward one another.

Brief Description Of The Drawings

These and other objects and features of the present invention will be more fully disclosed or rendered obvious by the following detailed description of the preferred embodiments of the invention, which is to be considered together with the accompanying drawings wherein like numbers refer to like parts and further wherein:

Fig. 1 is a schematic sectional view of a novel tunable Fabry-Perot filter formed in accordance with the present invention;

Fig. 2 is a schematic sectional view of a novel tunable VCSEL formed in accordance with the present invention;

Figs. 3-11 are schematic views illustrating fabrication of the tunable Fabry-Perot filter of Fig. 1, wherein Fig. 3 shows a bottom mirror mounted to the top of a substrate and a bottom electrode mounted to the top of the bottom mirror, Fig. 4 shows a sacrificial structure mounted to the top of the bottom electrode, Fig. 5 shows the sacrificial structure after it has had its peripheral edges modified, Fig. 6 shows a top electrode deposited on the top of the sacrificial structure, Fig. 7 shows a thin membrane support deposited on top of the sacrificial structure, the top electrode and a portion of the bottom electrode, Fig. 8 shows a central aperture formed in the thin membrane support, Fig. 9 shows a reinforcer deposited about the periphery of the thin membrane support, Fig. 10 shows the top of the device after openings have been etched

in the dome, and Fig. 11 shows a top mirror deposited on top of the thin membrane support;

Fig. 12 is a schematic side view showing another form of device formed in accordance with the present invention;

Fig. 13 is a schematic side view showing still another form of device formed in accordance with the present invention;

Fig. 14 is a schematic side view showing yet another form of device formed in accordance with the present invention;

Fig. 15 is a schematic sectional view taken through line 15-15 of Fig. 14;

Fig. 16 is a schematic side view showing another form of device formed in accordance with the present invention;

Fig. 17 is a schematic sectional view taken through line 17-17 of Fig. 16;

Fig. 18 is a schematic side view showing another form of device formed in accordance with the present invention; and

Fig. 19 is a schematic sectional view taken through line 19-19 of Fig. 18.

Detailed Description Of The Preferred Embodiments

Looking first at Fig. 1, there is shown a tunable Fabry-Perot filter 5 formed in accordance with the present invention. Filter 5 generally comprises a substrate 10, a bottom mirror 15 mounted to the top of substrate 10, a bottom electrode 20 mounted to the top of bottom mirror 15, a thin membrane support 25 atop bottom electrode 20, a top electrode 30 fixed to the underside of thin membrane support 25, a reinforcer 35 fixed to the outside perimeter of thin membrane support 25, and a confocal top mirror 40 set atop thin membrane support 25, with an air cavity 45 being formed between bottom mirror 15 and top mirror 40.

As a result of this construction, a Fabry-Perot cavity is effectively created between top mirror 40 and bottom mirror 15. Furthermore, by applying an appropriate voltage across top electrode 30 and bottom electrode 20, the position of top mirror 40 can be changed relative to bottom mirror 15, whereby to change the length of the Fabry-Perot cavity, and hence to tune Fabry-Perot filter 5.

Correspondingly, and looking next at Fig. 2, a tunable vertical cavity surface emitting laser (VCSEL) 50 can be constructed by appropriately modifying the construction of Fabry-Perot filter 5, i.e., by
5 positioning a gain region 55 between bottom mirror 15 and bottom electrode 20. As a result of this construction, when gain region 55 is appropriately stimulated, e.g., by optical pumping, lasing can be established within air cavity 45, between top mirror 40 and bottom mirror 15. Furthermore, by applying an appropriate voltage across top electrode 30 and bottom electrode 20, the position of top mirror 40 can be
10 changed relative to bottom mirror 15, whereby to change the length of the laser's resonant cavity, and hence to tune VCSEL 50.

If desired, thin membrane support 25 may be formed as a plurality of separate, relatively thin arms, and reinforcer 35 may be formed as corresponding peripheral posts.

20 In general, forming thin membrane support 25 as a plurality of separate, relatively thin arms has at least two advantages: (1) it is easier to gain chemical access to the region below thin membrane support 25,

whereby to form air cavity 45, and (2) it is easier to move top mirror 40 relative to bottom mirror 15 when an appropriate voltage is applied across top electrode 30 and bottom electrode 20, whereby to tune Fabry-Perot filter 5 or VCSEL 50.

In practice, however, it has been discovered that forming thin membrane support 25 as a plurality of separate, relatively thin arms presents several problems. For convenience, these problems can be collectively referred to as problems of "noise".

More particularly, it has been found that separate, relatively thin support arms tend to vibrate with the mechanical shocks which are frequently encountered in the real world. Such vibrations can cause top mirror 40 to move relative to bottom mirror 15, thereby causing Fabry-Perot filter 5 or VCSEL 50 to move in and out of "focus" or "tune".

Furthermore, as the power of Fabry-Perot filter 5 or VCSEL 50 rises, there can sometimes be a tendency for top mirror 40 to move upward relative to bottom mirror 15, thereby causing the device to move out of "focus" or "tune". In theory, the voltage applied to the device could be correspondingly increased so as to

compensate for this effect and bring the device back into "focus" or "tune", but in practice this has proven difficult to regulate. Furthermore, as the voltage applied to the device is increased, the curvature of top mirror 40 can change as well, thereby introducing new problems with device performance.

It has now been discovered that the larger the surface area of thin membrane support 25, and the stiffer it is, the better that the device can resist the "noise" problems described above. Accordingly, in accordance with the present invention, thin membrane support 25 is preferably fabricated in the form of a dome with openings therein, with the openings being small enough, and with sufficient distance therebetween, so as to substantially not affect the overall structural integrity of the dome, while still allowing chemical access to the region inside the dome.

In accordance with the present invention, a Fabry-Perot filter 5 (Fig. 1) may be formed as follows.

First, starting with a substrate 10 (Fig. 3), a bottom mirror 15 is mounted to the top of the substrate, and then a bottom electrode 20 is mounted to the top of bottom mirror 15. Substrate 10 preferably

comprises a semiconductor material such as Si, GaAs, InP or other suitable materials. Bottom mirror 15 preferably comprises a distributed Bragg reflector (DBR) formed out of alternating layers of quarter-wavelength thick deposited dielectric films, e.g., silicon (Si) and aluminum oxide (Al_2O_3), or silicon (Si) and silicon dioxide (SiO_2), or silicon (Si) and magnesium oxide (MgO), or TiO_2 and SiO_2 , or Ta_2O_5 or zirconium oxide, etc. Bottom mirror 15 may be deposited on substrate 10 by any suitable thin film deposition techniques. Bottom electrode 20 includes a central aperture 58.

Next, a sacrificial structure 60 (Fig. 4) of polyimide, or aluminum, or some other sacrificial material, is deposited on top of bottom electrode 20 (and, in the region of central aperture 58, bottom mirror 15). The sacrificial structure 60 will act as a sacrificial layer to be removed later in the fabrication process, as described in detail below. It should be appreciated that it is important to accurately control the thickness and lateral dimensions of sacrificial structure 60. This is because the thickness of sacrificial structure 60 will determine

the ultimate length of the air cavity 45 in the tunable Fabry-Perot device and, hence, the unbiased resonant wavelength of the device. On the other hand, the lateral dimension of sacrificial structure 60 will
5 determined the voltage response of the device and the resonance frequency. Sacrificial structure 60 preferably has a circular configuration when viewed from the top (although it may, alternatively, have a polygonal configuration if desired). Sacrificial structure 60 may be deposited on bottom electrode 20
10 (and, in the region of central aperture 58, bottom mirror 15) by evaporation or standard coating methods.

An etch-mask is then used to pattern sacrificial structure 60 so as to leave a circular (or, alternatively, polygonal) disk-shaped deposit defining an outwardly slanted edge 65 on its etched perimeter
15 (Fig. 5). Slanted edge 65 preferably extends at an angle of approximately 45 degrees to the top surface of bottom electrode 20.

20 Next, top electrode 30 is deposited on sacrificial structure 60 (Fig. 6). Top electrode 30 may be deposited directly on the top surface of sacrificial structure 60, or top electrode 30 may be deposited into

a recess formed in the top surface of sacrificial structure 60, e.g., in the manner shown in Fig. 6. Top electrode 30 preferably has a washer-like configuration, i.e., it preferably has a circular outer perimeter and a circular inner hole.

Thereafter, thin membrane support 25 (Fig. 7) is deposited over sacrificial structure 60, top electrode 30 and a portion of bottom electrode 20. Due to the structure of the underlying elements, thin membrane support 25 essentially has a dome configuration. Thin membrane support 25 comprises a material different than the material used to form sacrificial structure 60. By way of example but not limitation, thin membrane support 25 may comprise silicon nitride or a metal, e.g., titanium-tungsten (TiW). Thin membrane support 25 may be deposited on sacrificial structure 60, top electrode 30 and bottom electrode 20 by standard deposition techniques.

In the case where thin membrane support 25 is formed out of a material which is not transparent, the center portion is removed (Fig. 8) so as to form an aperture 67.

Next, a reinforcer 35 (Fig. 9) made of metal (such as Al or TiW) or a hard dielectric (such as silicon nitride) is selectively deposited on the periphery of thin membrane support 25 so as to form an annular peripheral rim which essentially covers and supports the peripheral portion of thin membrane support 25. The lateral dimension of reinforcer 35 is selected such that a thick metal rim extends from bottom electrode 20, up over the sloped edge 65 of sacrificial structure 60, and up onto the top of the structure, as indicated in Fig. 9. The thick reinforcer 35 (formed out of metal or a hard dielectric) provides robust support for thin membrane support 25 (formed out of silicon nitride or TiW) after the underlying sacrificial structure 60 has been removed (see below). Reinforcer 35 may be deposited on thin membrane support 25 (and, at the periphery of reinforcer 35, bottom electrode 20) by standard deposition techniques.

In essence, thin membrane support 25 comprises a thin dome structure, and reinforcer 35 comprises a thick rim support for the periphery of thin membrane support 25.

Using an etch-mask, a plurality of small openings 70 (only several of which are numbered in Fig. 10) are then formed by etching through thin membrane support 25, down to the underlying sacrificial structure 60.

5 These openings 70 provide gateways for etchants to selectively remove the underlying sacrificial structure 60, as will hereinafter be discussed in further detail. Openings 70 preferably have a circular configuration, although they may also have a polygonal configuration if desired.

10 Circular openings 70 are formed small enough, and with sufficient distance therebetween, so as to substantially not affect the overall structural integrity of the dome structure of thin membrane support 25, while still allowing chemical access to the region inside the dome.

15 If desired, openings 70 may also be formed in reinforcer 35. To the extent that openings 70 are formed in reinforcer 35, these openings are sized and spaced so as to substantially not affect the structural integrity of the rim structure of reinforcer 35.

20 Next, a circular top mirror 40 is then selectively deposited at the center of thin membrane support 25

(Fig. 11). In one preferred form of the invention, top mirror 40 comprises a distributed Bragg reflector (DBR) formed out of alternating layers of quarter-wavelength thick deposited dielectric films, e.g., silicon (Si) and aluminum oxide (Al_2O_3), or silicon (Si) and silicon dioxide (SiO_2), or silicon (Si) and magnesium oxide (MgO), or TiO_2 and SiO_2 , or Ta_2O_5 or zirconium oxide, etc. Top mirror 40 may be deposited on thin membrane support 25 by thin film coating technology.

Top mirror 40 is preferably curved. More particularly, top mirror 40 is preferably curved so that the curved top mirror 40, in combination with the planar bottom mirror 15, together form a confocal stable resonator with a well-defined, near-Gaussian mode structure. In one preferred form of the invention, top mirror 40 has a radius of curvature, with the radius of curvature being optimized so that the mode size of the cavity matches the size of the core of an optical fiber.

To the extent that top mirror 40 is to assume a curved configuration in the completed device (e.g., as shown in Figs. 1 and 11), an appropriate magnitude and type of strain is introduced into top mirror 40 during

deposition of the top mirror. This may be accomplished by controlled changes in deposition temperatures or deposition voltages.

5 Finally, an etchant is used to selectively remove sacrificial layer 60 and form air gap 45 (Fig. 1). This etchant is introduced to the area under thin membrane support 25 via openings 70, and may comprise an oxygen plasma (in the case where sacrificial structure 60 comprises polyimide) or a CF_4 plasma (in the case where sacrificial structure 60 comprises aluminum). This releases thin membrane support 25 along with top mirror 40. To the extent that top mirror 40 is formed with an appropriate magnitude and type of strain to result in the formation of a curved configuration, the removal of sacrificial structure 60 permits the top mirror to assume its desired curved configuration. Since wet chemistry is, preferably, not involved in removing sacrificial structure 60, there is no risk of the released thin membrane support 25 collapsing due to surface tension.

20 This completes the fabrication of a tunable Fabry-Perot filter.

5 A tunable VCSEL (Fig. 2) may be formed in
corresponding fashion by depositing a gain region 55
between bottom mirror 15 and bottom electrode 20. Gain
region 55 may comprise an InGaAsP/InGaAs multiple
quantum well (MQW) structure. Gain region 55 may be
deposited on bottom mirror 15 by MBE (molecular beam
epitaxy) or MOCVD (metal organic chemical vapor
deposition) methods, and bottom mirror 20 may be
deposited on gain region 55 by MBE or MOCVD or other
10 thin film coating techniques. Lasing can be achieved
by photo-pumping with a separate pump laser having a
wavelength that is highly absorptive within the gain
spectrum of the gain medium used in gain region 55.

15 The present invention can also be used to produce
a current-injected tunable VCSEL as well. In this
situation, intra-cavity electrical interconnections are
made to the p-i-n junction in the gain structure.

20 In accordance with the present invention, it has
now been discovered that tunable Fabry-Perot filters
and tunable lasers utilizing a dome structure of the
sort described above have certain limitations with
respect to their tuning range. More particularly, when
the bias (i.e., tuning) voltage of the device exceeds a

certain threshold, the thin membrane support 25 will exceed its elastic limit and snap. It is believed that this occurs because as the thin membrane support deforms, the electrostatic force is increasingly concentrated in the area of the deflected beam so that, at a particular bias voltage, the concentrated load causes the thin membrane support 25 to become unstable. Increasing the bias voltage above this level causes the thin membrane support 25 to snap. With constructions such as those shown in Figs. 1 and 2, this limit is typically reached when the deflection is approximately one-third of the original electrode-electrode (i.e., top electrode 30 - bottom electrode 20) separation.

Looking now at Fig. 12, there is shown an alternative construction for increasing the tuning range of a tunable Fabry-Perot filter and tunable VCSEL. In essence, this construction increases the spacing between the bias electrodes (i.e., between top electrode 30 and bottom electrode 20) while maintaining the spacing between the functional optical elements (i.e., top mirror 40 and bottom mirror 15 and, in the case of a tunable VCSEL, gain region 55). More particularly, the geometry of the dome is modified so

as to move top electrode 30 further away from bottom
electrode 20 while keeping the spacing between top
mirror 40 and bottom mirror 15 substantially the same.
Thus, the spacing between the bias electrodes is
increased without changing the spacing between the
functional optical components, thereby effectively
increasing the tuning range of the device without
affecting the optical performance of the device.

Looking next at Fig. 13, there is shown another
alternative construction for increasing the tuning
range of a tunable Fabry-Perot filter and tunable
VCSEL. Again, this construction increases the spacing
between the bias electrodes (i.e., between top
electrode 30 and bottom electrode 20) while maintaining
the spacing between the functional optical elements
(i.e., top mirror 40 and bottom mirror 15 and, in the
case of a tunable VCSEL, gain region 55). More
particularly, the geometry of the base is modified so
as to move bottom electrode 20 further away from top
electrode 30 while keeping the spacing between top
mirror 40 and bottom mirror 15 substantially the same.
Thus, the spacing between the bias electrodes is
increased without changing the spacing between the

functional optical components, thereby effectively increasing the tuning range of the device without affecting the optical performance of the device.

5 With the alternative constructions shown in Figs. 12 and 13, the planar natures of the tuning electrodes (i.e., top electrode 30 and bottom electrode 20) have been maintained while moving the tuning electrodes further apart from one another. However, inasmuch as electrostatic force is inversely proportional to the square of the tuning distance, larger electrostatic forces must then be generated for corresponding movement of the optical components.

10 Looking next at Figs. 14 and 15, there is shown another alternative construction for increasing the tuning range of a tunable Fabry-Perot filter and tunable VCSEL. In essence, this construction modifies the geometry of the bias electrodes while maintaining the spacing between the functional optical elements. More particularly, the geometries of top electrode 30 and bottom electrode 20 are modified so as to comprise interdigitized fingers while keeping the spacing between top mirror 40 and bottom mirror 15 substantially the same. This construction means that

the pulling force is effectively independent of the tuning distance so long as the degree of finger interdigitation is reasonable. Electrode fingers can be created by forming top electrode 30 and bottom electrode 20 so as a series of concentric circles in the manner shown in Figs. 14 and 15, or as a series of parallel plates in the manner shown in Figs. 16 and 17, or as a plurality of interspaced posts in the manner shown in Figs. 18 and 19, etc.

It will be understood that the foregoing detailed description of the preferred embodiments of the invention has been presented by way of illustration and not limitation. Various modifications, variations, changes, adaptations and the like will occur to those skilled in the art in view of the foregoing specification. Accordingly, the present invention should be understood as being limited only by the terms of the claims.